



Sonderforschungsbereich 595

Elektrische Ermüdung  
in Funktionswerkstoffen



TECHNISCHE  
UNIVERSITÄT  
DARMSTADT



**SFB 595 Kolloquium  
in cooperation with GRK 1037**

**05. Juli 2007, 14.45 Uhr**

**Gebäude der  
Materialwissenschaften**

**Raum 77**

**Leakage currents through metal/insulator/metal (MIM) thin film  
capacitor stacks**

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The present understanding of steady state leakage currents through metal/insulator/metal thin film (MIM) capacitor stacks with high permittivity dielectrics or ferroelectrics will be reviewed. Such capacitor stacks have gained increasing attention because of possible future applications in dynamic random access memory (DRAM) devices or as new gate (oxid-)materials in metal-oxid-semiconductor field-effect transistors (MOSFET).

The first part consist of a discussion of the experimental conditions to measure the *true* leakage current and from that, necessary conditions will be extracted to create reliable leakage current data for mechanistic studies. In the second part the most common leakage current mechanisms will be introduced with special emphasis on the characteristic parameters for experimental verification. The third part will give some selected examples of experimental data and possible difficulties in identifying the controlling mechanism. In a fourth part a (new) model is offered combining carrier injection by thermionic emission and/or tunnelling at the electrode interface with the transport properties of the film bulk, which can be described by drift and diffusion with an effective mobility/diffusivity such as band or large-polaron conduction. Model simulation results are compared to experimental data.

In a last part a new non-volatile memory device, the current controlled resistive RAM (possibly replacing the volatile DRAM) will be introduced and described.